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H. F. HORN ETAL
PROCESS FOR THE VAPOR DEPOSITION OF MATERIAL WITHOUT
THERMAL RADIATION OF THE SUBSTRATE
Filed Jan. 14, 1963

3,333,982

Fig. 1

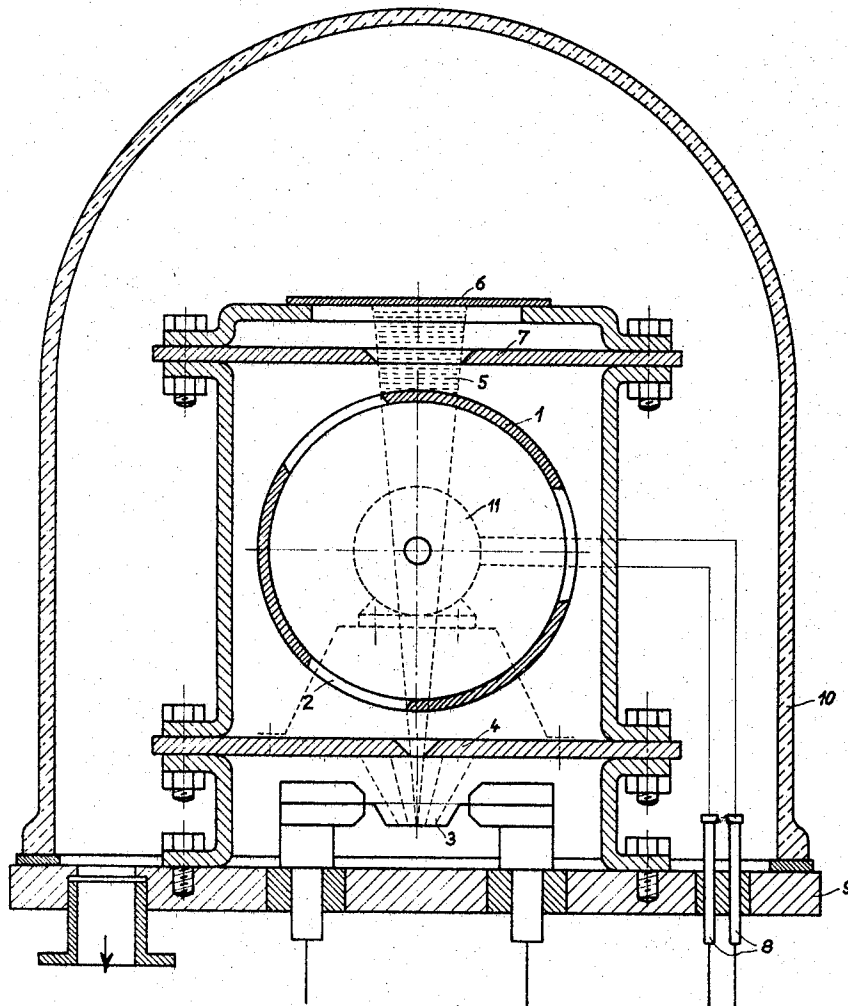
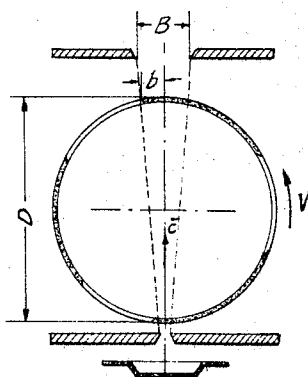


Fig. 2



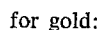
Inventors
H. F. Horn
A. F. Aldrian
By
Watson, Cole, Grindler & Watson
Attys.

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1 Claim. (Cl. 117—106)

The same goal is achieved with two disks rigidly connected by a common shaft when the disks are provided with openings adjustable with respect to one another about an appropriate angle. These disks are displaced

This value can be calculated from the Maxwell equation



With reference to the diagram as shown on FIG. 2, this is for the purpose to indicate and satisfy the conditions that light never can pass the upper diaphragm and

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that the vapour-rays here possess a diameter B. Then the rotating cylinder (diameter D) even when it overlaps the lower diaphragm just overlaps the upper diaphragm by the distance b . A vapour-impulse which enters the cylinder through the lower diaphragm passes through the cylinder while it rotates by the distance b . In this way the vapour-impulse is able to leave the cylinder. Therefore the distance b represents an apparatus constant depending only on v (velocity on the periphery of the rotating cylinder) and on \bar{v} (velocity of the vapour-rays). 5 10

We claim:

Process for depositing thin layers by thermal vaporization without thermal radiation loading of the receiver comprising separating the vapor waves coming from the vapor source from the accompanying heat waves by decomposing both types of waves simultaneously into impulses of definite length, and catching the more rapid 15

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and therefore preceding heat wave impulses by a moving screen system while the relatively slower vapor wave impulses are allowed to pass through unhindered.

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ALFRED L. LEAVITT, *Primary Examiner.*

RICHARD D. NEVIUS, *Examiner.*

M. KAPLAN, J. P. MCINTOSH, W. L. JARVIS,
Assistant Examiners.